

Admittance Spectroscopy and Deep-Level Transient Spectroscopy in Multijunction: a Tutorial to Characterize the Entire Cell

Cyril Léon, Sylvain Le Gall, Marie-Estelle Gueunier-Farret, Jean-Paul Kleider

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What is wrong with the first approach ?

• **Voltage distribution:** Depends on the unknown *J*(*V*) of each subcell.

• **Capacitance coupling:**

The measured capacitance results in a coupling of both unknown subcells capacitance. Leading to mixed, shifted or invisible defect signatures.

• **Impact of the temperature:**

The temperature can increase the diffusion phenomena leading to an artefact in the measurement that can be mistaken as the signature of a defect.

• **Filling pulse distribution:** Depends on the unknown capacitance values of each subcell.

Too many unknown & unmonitored parameters

Frequency (Hz)

Cyril Leon^{1,2}, Sylvain Le Gall¹, Marie-Estelle Gueunier-Farret¹, Jean-Paul Kleider¹. ¹Group of electrical engineering - Paris (GeePs), CNRS, CentraleSupélec, Univ. Paris-Saclay, Sorbonne Univ., 11 rue Joliot-Curie, 91192 Gifsur-Yvette, France.

For John, only the defect in the Si cell can be seen but with errors in AS.

In John's case, 90 % of the filling pulse only apply on the Si cell and not on the AlGaAs cell.

Poor John, by mistake, he probed the wrong subcell with errors and artefacts !

 $\overset{\text{L}}{=}$ 4x10⁻⁸

 $2x10^{-8}$

 \circ

 $C_{2T} = 0$

10⁶

Frequency (Hz)

 $1x10^{-9}$

100

200

300

Temperature (K)

Admittance Spectroscopy and Deep-Level Transient Spectroscopy in Multijunction

A Tutorial to Characterize the Entire Cell

AlGaAs cell Si cell $\omega_{\rm Sh}$ 1/ $\tau_{\rm eff,2}$ $\omega_{\rm HF}$ 1.4x10 1.2×10^{-7} Single Bottom $1.0x10$ $\text{-} \mathsf{TSC}_\infty$ 8.0x10 6.0x10 $4.0x10^{-8}$ \cdot - - Single Top $2.0x10^{-8}$ $--- (1/C + 1/C)$ Frequency (Hz)

²Aix Marseille University, CNRS, IM2NP Campus de Saint Jérôme, Case 142, 13397 Marseille Cedex 20, France

• Thanks to TCAD modeling, we will assist John in his mission **to get the same results while working on the whole**

• **John wants to get the defect properties of the AlGaAs subcell within his 2T tandem cell** using Admittance Spectroscopy (AS) and Deep-Level Transient Spectroscopy (DLTS).

• He doesn't know yet that within the AlGaAs subcell, a 0.5 eV deep defect is present. **If he could characterize this subcell alone, he would get:**

> The subcell in the dark limits the current, forcing the absorbing subcell to be polarized at its V_{OC} . The voltage in the probed cell is: $V_{\text{probe}} = V_{\text{applied}} - V_{\text{OC,Biased}}.$

tandemPV Workshop 2022 May 30 – June 1 | 2022 Freiburg, Germany leon_cyril**@**hotmail.fr

Curriculum Vitae

Conclusions

Under the IR laser, John measures $V_{OCSi} = 0.5$ *V. He knows that in DLTS, to apply a filling pulse between -1 V and 0 V on the AlGaAs cell he has to apply on the whole tandem a filling pulse between -0.5V and 0.5V.*

• **In the dark,** signals of each subcell are mixed leading to **wrong defect signatures**.

- **Under well chosen light biases,** the absorbing subcells can be shunted and only **the one that remains in the dark is probed.**
- *My mission is now complete and I am looking for a new one! (Available from September)*

Jobs

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Using light biases

Changes the electrical behavior of the tandem

Diffusion phenomena in a subcell:

(28) 2020

- Caused by the temperature in the dark (uncontrolled).
- Caused by a forward polarization (controlled using light bias). **Shunts the absorbing subcells**

C. Leon *et al.* **Prog Photovolt Res Appl** This has been **experimentally** validated by extracting the doping \Box densities in an AlGaAs/Si tandem cells using $C(V)$. Here we extend the $\frac{1}{2}$ method to AS and DLTS.

First approach

John simply places his tandem cell in his AS and DLTS setup and performs the measurments. He obtains:

Measuring a tandem cell like a single junction

Poor John! **He did not get the expected results.** Also, he is damn wrong with his conclusions.

We suggested John to read this article: **C. Leon** *et al.* **SolMat 240, 11699 (2022)**

Now, he knows that he needs to light bias the subcell that he does not want to probe.

Step by step tutorial

Step 1: Read

Step 2: Let there be light!

Step 3: Measure & correct the voltage shift

Example: He uses an IR laser to light bias the bottom Si cell and probe the top AlGaAs cell.

Step 4: Optimization

• Diffusion phenomena in the absorbing subcell can shunt its capacitance.

• But also creates an inflexion in AS curves and a transient evolution in DLTS.

• These artefacts can be excluded from the measurement range by increasing the light intensity.

John measures C(f) and C(t) curves at room temperature. He notices some artefacts that shift when increasing the light intensity of the laser. He observes that at 100 mW, the artefacts are out of the frequency and time range of the measurement.

Time (s)

Context & principles AS DLTS

• AS and DLTS are two characterization techniques **to extract information on the defects** electrically active in a semiconductor.

• Although these techniques are widely used to characterize simple devices, **they have never been used to characterize multijunctions.**

Frequency Time Temperature The variation of inflexions and pics with T gives **Ea (the defect position)**